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GROUP 1700

1763

PATENT
Customer No. 22,852
Attorney Docket No. 07553.0010

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Saito *et al.*) Group Art Unit: 1763
Application No.: 09/686,370) Examiner: R. Kackar
Filed: October 12, 2000)
For: Processing Apparatus for)
Conservation of Processing Gases)
(As Amended)

#131
5/23/03
mw

Commissioner for Patents
Washington, DC 20231

Sir:

AMENDMENT

In reply to the Office Action dated February 21, 2003, please amend the application as follows:

IN THE CLAIMS:

Please add new claim 24 as set forth below.

Please amend claims 1, 14, and 15 to read as follows:

1. (Four Times Amended) A processing apparatus comprising:

D1 a gas supply mechanism that supplies a processing gas into a processing chamber via a plurality of gas supply holes including a plurality of primary gas supply holes and a plurality of circulating gas supply holes,